Notice of Allowability	Application No.	Applicant(s)
	09/965,803	TANAKA, KAZUHIRO
	Examiner	Art Unit
	Roberts Culbert	1763
The MAILING DATE of this communication apperature All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIOF of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate commits GHTS. This application is	n this application. If not included unication will be mailed in due course. <b>THIS</b>
1. This communication is responsive to the amendment filed	<u>3/9/05</u> .	
2. The allowed claim(s) is/are 14 and 17-19.		
3. The drawings filed on <u>01 October 2001</u> are accepted by the Examiner.		
<ul> <li>4.  Acknowledgment is made of a claim for foreign priority una)  All b)  Some* c)  None of the: <ol> <li>Certified copies of the priority documents have</li> <li>Certified copies of the priority documents have</li> <li>Copies of the certified copies of the priority documents have</li> </ol> </li> <li>Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)).</li> </ul> <li>* Certified copies not received:</li>	been received. been received in Application	on No
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file ENT of this application.	e a reply complying with the requirements
5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
<ol> <li>CORRECTED DRAWINGS (as "replacement sheets") mus</li> <li>(a) ☐ including changes required by the Notice of Draftspers</li> <li>1) ☐ hereto or 2) ☐ to Paper No./Mail Date</li> <li>(b) ☐ including changes required by the attached Examiner's Paper No./Mail Date</li> </ol>	on's Patent Drawing Revie	
Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the	84(c)) should be written on t ne header according to 37 CF	he drawings in the front (not the back) of R 1.121(d).
7. DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT I	SIT OF BIOLOGICAL MATE FOR THE DEPOSIT OF BIO	ERIAL must be submitted. Note the DLOGICAL MATERIAL.
Attachment(s)  1. ☐ Notice of References Cited (PTO-892)  2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)  3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/06 Paper No./Mail Date  4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. ☐ Interview S Paper No./ 3), 7. ☐ Examiner's	formal Patent Application (PTO-152)  ummary (PTO-413),  'Mail Date Amendment/Comment  Statement of Reasons for Allowance
U.S. Patent and Trademark Office PTOL-37 (Rev. 1-04) Not	ice of Allowability	Part of Paper No./Mail Date 0405

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Allowable Subject Matter

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Claims 14 and 17-19 are allowed.

The following is an examiner's statement of reasons for allowance:

The prior art of record fails to teach or render obvious a method of chemical mechanical polishing comprising: supplying slurry including polishing particles to a polishing apparatus including a polisher and an object to be polished; measuring particle information including at least one of dispersion of the polishing particles and distribution of particle sizes of the polishing particles of the slurry that is directly supplied to the in the polishing apparatus; and controlling the polishing speed at which the object is being polished, based on the particle information by adjusting at least one of rotation speed of the polisher, rotation speed of the object, and force applied by the polisher to the object.

Applicant's arguments (pages 3-5) regarding the previous rejection of claim 14 based on Yueh alone have been considered, but are not persuasive. Yueh contains an enabling disclosure as would be recognized by one of ordinary skill in the art of chemical mechanical polishing and process control. However, the argument is most since applicant has amended claim 14 to include limitations of claim 16, which was previously rejected over Yueh in view of Shelton. The combination of Yueh and Shelton to arrive at the invention of amended claim 14 is deemed improper, since Shelton does not measure the dispersion or distribution of polishing particles of slurry that is directly supplied to the object, but instead detects for the presence of particles that are in the polished object.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Roberts Culbert whose telephone number is (571) 272-1433. The examiner can normally be reached on Monday-Friday (8:30-5:00).

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor,

Parviz Hassanzadeh can be reached on (571) 272-1435. The fax phone number for the organization

where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application

Information Retrieval (PAIR) system. Status information for published applications may be obtained from

either Private PAIR or Public PAIR. Status information for unpublished applications is available through

Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should

you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC)

at 866-217-9197 (toll-free).

R. Culbert

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PARVIZ HASSENZADEH
SUPERVISORY PATENT EXAMINER

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